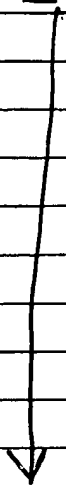
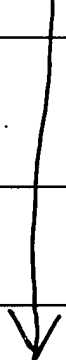


<b>INFORMATION DISCLOSURE CITATION</b>  <b>PTO-1449</b>  <b>SHEET 1 OF 2</b>		ATTY. DOCKET NO. P128-US		SERIAL NO. Not Yet Assigned			
		APPLICANT Jonathan Doan					
		FILING DATE Herewith		GROUP Not Yet Assigned			
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Eric Ann ↓			12/6/05				
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			APPLICANT Jonathan Doan				
			FILING DATE Herewith		GROUP Not Yet Assigned		
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<b>INFORMATION DISCLOSURE CITATION</b> PTO-1449 APR 27 2005 U.S. PATENT & TRADEMARK SERVICE		ATTY. DOCKET NO. P128-US		SERIAL NO. 10/766,776			
		APPLICANT Doan, et al.					
		FILING DATE 1/27/04		GROUP Not Yet Assigned			
SHEET 1 OF 2							
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<b>INFORMATION DISCLOSURE CITATION</b>  <b>PTO-1449</b>  <b>SHEET 2 OF 2</b>		ATTY. DOCKET NO. P128-US		SERIAL NO. 10/766,776			
		APPLICANT Doan, et al.					
		FILING DATE 1/27/04		GROUP Not Yet Assigned			
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EXAMINER <i>Eric Alm</i>				DATE CONSIDERED 12/6/05			

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